

Carlos Dominguez

List of Publications by Year in descending order

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214
papers

4,389
citations

101543

36
h-index

138484

58
g-index

217
all docs

217
docs citations

217
times ranked

3900
citing authors

#	ARTICLE	IF	CITATIONS
1	Nanoporous silk films with capillary action and size-exclusion capacity for sensitive glucose determination in whole blood. Lab on A Chip, 2021, 21, 608-615.	6.0	9
2	Reconfigurable reflective arrayed waveguide grating (R-RAWG). , 2021, , .		0
3	Embedded Silicon Nanoparticles as Enabler of a Novel CMOS-Compatible Fully Integrated Silicon Photonics Platform. Crystals, 2021, 11, 630.	2.2	5
4	Study of waveguide background at visible wavelengths for on-chip nanoscopy. Optics Express, 2021, 29, 20735.	3.4	4
5	Thermo-Optic Phase Tuners Analysis and Design for Process Modules on a Silicon Nitride Platform. Photonics, 2021, 8, 496.	2.0	4
6	Sagnac Reflector Based Broadband Tunable Integrated Mirror. , 2020, , .		0
7	Photoelectro-Enzymatic Glucose Reusable Biosensor by Using Dithienylethene Mediators. Chemistry - A European Journal, 2020, 26, 8714-8719.	3.3	3
8	Reconfigurable reflective arrayed waveguide grating using optimization algorithms. Optics Express, 2020, 28, 31446.	3.4	5
9	Open-Access Silicon Photonics Platforms in Europe. IEEE Journal of Selected Topics in Quantum Electronics, 2019, 25, 1-18.	2.9	82
10	Foundry Developments Toward Silicon Nitride Photonics From Visible to the Mid-Infrared. IEEE Journal of Selected Topics in Quantum Electronics, 2019, 25, 1-13.	2.9	47
11	Reconfigurable multiplexed point of Care System for monitoring type 1 diabetes patients. Biosensors and Bioelectronics, 2019, 136, 38-46.	10.1	15
12	Luminescence from Si-Implanted SiO ₂ -Si ₃ N ₄ Nano Bi-Layers for Electrophotonic Integrated Si Light Sources. Sensors, 2019, 19, 865.	3.8	4
13	Low-cost vertical taper for highly efficient light in-coupling in bimodal nanointerferometric waveguide biosensors. JPhys Photonics, 2019, 1, 025002.	4.6	7
14	Refractive index sensing using a Si-based light source embedded in a fully integrated monolithic transceiver. AIP Advances, 2019, 9, .	1.3	5
15	Low-loss inverted taper edge coupler in silicon nitride. IET Optoelectronics, 2019, 13, 62-66.	3.3	8
16	[INVITED] Silicon nitride photonic integration for visible light applications. Optics and Laser Technology, 2019, 112, 299-306.	4.6	74
17	Silk Fibroin Pads for Whole Blood Glucose Determination. Proceedings (mdpi), 2018, 2, .	0.2	2
18	Advanced Integrated Testing Engine Towards a Complete Characterization of Photonic Integrated Devices. , 2018, , .		0

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19	Cost-effective smartphone-based reconfigurable electrochemical instrument for alcohol determination in whole blood samples. <i>Biosensors and Bioelectronics</i> , 2018, 117, 736-742.	10.1	40
20	Silicon nitride photonics: from visible to mid-infrared wavelengths. , 2018, , .		3
21	Electrodepositable alginate membranes for enzymatic sensors: An amperometric glucose biosensor for whole blood analysis. <i>Biosensors and Bioelectronics</i> , 2017, 97, 136-142.	10.1	64
22	Array of Microfluidic Beam Resonators for Density and Viscosity Analysis of Liquids. <i>Journal of Microelectromechanical Systems</i> , 2017, 26, 749-757.	2.5	4
23	Asymmetrically coupled resonators for mass sensing. <i>Applied Physics Letters</i> , 2017, 111, .	3.3	39
24	Influence of the gate and dielectric thickness on the electro-optical performance of SRO-based LECs: Resistive switching, IR and deep UV emission. <i>Journal of Luminescence</i> , 2017, 192, 919-924.	3.1	13
25	State of the art of Silicon Nitride photonics integration platforms. , 2017, , .		5
26	Enhancing emission and conduction of light emitting capacitors by multilayered structures of silicon rich oxide. <i>Sensors and Actuators A: Physical</i> , 2017, 265, 306-312.	4.1	6
27	Hot electron engineering for boosting electroluminescence efficiencies of silicon-rich nitride light emitting devices. <i>Journal of Luminescence</i> , 2017, 183, 26-31.	3.1	6
28	Study of narrow and intense UV electroluminescence from ITO/SRO/Si-p and ITO/SRN/SRO/Si-p based light emitting capacitors. <i>Journal of Luminescence</i> , 2017, 183, 334-340.	3.1	7
29	Silicon Nitride Photonic Integration Platforms for Visible, Near-Infrared and Mid-Infrared Applications. <i>Sensors</i> , 2017, 17, 2088.	3.8	202
30	Vertical adiabatic taper for efficient in-coupling in nano-interferometric waveguide biosensors. , 2017, , .		0
31	Linear propagation properties for a 300 nm film height Silicon Nitride photonic integration platform in the optical telecom C-band. , 2017, , .		0
32	Enzymatic Biosensors Based on Electrodeposited Alginate Hydrogels. <i>Procedia Engineering</i> , 2016, 168, 622-625.	1.2	6
33	Impact of the Structural Characteristics on the Performance of Light Emitting Capacitors Using Nanometric SRO Multilayers Fabricated by LPCVD. <i>Procedia Engineering</i> , 2016, 168, 1098-1101.	1.2	1
34	Effect of the active layer thickness on the electrical and electroluminescent properties in silicon rich oxide based light emitting capacitors. , 2016, , .		2
35	Structural and optical properties of silicon rich oxide films in graded-stoichiometric multilayers for optoelectronic devices. <i>Applied Physics Letters</i> , 2016, 109, 031906.	3.3	6
36	Label-free bimodal waveguide immunosensor for rapid diagnosis of bacterial infections in cirrhotic patients. <i>Biosensors and Bioelectronics</i> , 2016, 85, 310-316.	10.1	51

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37	Out-of-plane single-mode photonic microcantilevers for integrated nanomechanical sensing platform. Sensors and Actuators B: Chemical, 2016, 232, 60-67.	7.8	9
38	Monolithic Integration of a Silicon-Based Photonic Transceiver in a CMOS Process. IEEE Photonics Journal, 2016, 8, 1-13.	2.0	27
39	Synthesis of sol-gel SiO ₂ -based materials using alkoxydisilane precursors: mechanisms and luminescence studies. Journal of Sol-Gel Science and Technology, 2015, 73, 417-427.	2.4	4
40	Simulation and characterization of hollow microbridge resonators for label-free biosensing. , 2015, , .		0
41	Sensitivity analysis for improving nanomechanical photonic transducers biosensors. Journal Physics D: Applied Physics, 2015, 48, 335401.	2.8	8
42	Towards a biosensing multiple platform based on an array of hollow microbridge resonators. , 2014, , .		3
43	Composition and emission characterization and computational simulation of silicon rich oxide films obtained by LPCVD. Surface and Interface Analysis, 2014, 46, 216-223.	1.8	9
44	Conservation of the Optical Properties of SRO after CMOS IC Processing. Procedia Technology, 2014, 17, 587-594.	1.1	3
45	Wavelength Modulated Bimodal Interferometer for Highly Sensitive Biosensing Applications. , 2014, , .		0
46	DC Electroluminescence Efficiency of Silicon Rich Silicon Oxide Light Emitting Capacitors. Journal of Lightwave Technology, 2013, 31, 2913-2918.	4.6	8
47	Enhancement of light extraction in silicon-rich oxide light-emitting diodes by one-dimensional photonic crystal gratings. , 2013, , .		0
48	A comparative study of in-flow and micro-patterning biofunctionalization protocols for nanophotonic silicon-based biosensors. Journal of Colloid and Interface Science, 2013, 393, 402-410.	9.4	26
49	Floating substrate luminescence from silicon rich oxide metal-oxide-semiconductor devices. Thin Solid Films, 2013, 531, 442-445.	1.8	4
50	Influence by Layer Structure on the Output EL of CMOS Compatible Silicon-Based Light Emitters. IEEE Transactions on Electron Devices, 2013, 60, 1971-1974.	3.0	7
51	Grating couplers integrated on Mach-Zehnder interferometric biosensors operating in the visible range. IEEE Photonics Journal, 2013, 5, 3700108-3700108.	2.0	30
52	The effect of absorption and coherent interference in the photoluminescence and electroluminescence spectra of SRO/SRN MIS capacitors. Optics Express, 2013, 21, 10111.	3.4	3
53	Laser emission in Nd ³⁺ -doped barium-titanium-silicate microspheres under continuous and chopped wave pumping in a non-coupled pumping scheme. Laser Physics, 2013, 23, 075801.	1.2	11
54	Multiplexed Integrated Interferometers for Advanced Lab-on-a-Chip Biosensors. , 2013, , .		0

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55	Electroluminescence from Si-based light emitting devices. <i>Optica Pura Y Aplicada</i> , 2013, 46, 315-319.	0.1	0
56	On the Origin of Light Emission in Silicon Rich Oxide Obtained by Low-Pressure Chemical Vapor Deposition. <i>Journal of Nanomaterials</i> , 2012, 2012, 1-11.	2.7	22
57	Optically active $\hat{1}/4$ -disks resonators-based sensor for refractive index variation detection. , 2012, , .		0
58	Correlation between charge transport and electroluminescence properties of Si-rich oxide/nitride/oxide-based light emitting capacitors. <i>Journal of Applied Physics</i> , 2012, 112, 033114.	2.5	15
59	Influence of Silicon Binding Energy on Photoluminescence of Si-Implanted Silicon Dioxide. <i>ECS Transactions</i> , 2012, 49, 307-314.	0.5	3
60	Comparison of electrical and electro-optical characteristics of light-emitting capacitors based on silicon-rich Si-oxide fabricated by plasma-enhanced chemical vapor deposition and ion implantation. <i>Journal of Applied Physics</i> , 2012, 111, 053109.	2.5	11
61	Nanophotonic lab-on-a-chip platforms including novel bimodal interferometers, microfluidics and grating couplers. <i>Lab on A Chip</i> , 2012, 12, 1987.	6.0	82
62	One-Step Patterning of Hybrid Xerogel Materials for the Fabrication of Disposable Solid-State Light Emitters. <i>ACS Applied Materials & Interfaces</i> , 2012, 4, 5029-5037.	8.0	9
63	Bulk silica-based luminescent materials by sol-gel processing of non-conventional precursors. <i>Applied Physics Letters</i> , 2012, 101, 171908.	3.3	3
64	Interferometric waveguide biosensors based on Si-technology for point-of-care diagnostic. <i>Proceedings of SPIE</i> , 2012, , .	0.8	9
65	Visible Light Emitting Si-Rich Si ₃ N ₄ μ -Disk Resonators for Sensoristic Applications. <i>Journal of Lightwave Technology</i> , 2012, 30, 169-174.	4.6	3
66	Towards a complete Lab-On-Chip system using integrated Mach-Zehnder interferometers. <i>Optica Pura Y Aplicada</i> , 2012, 45, 87-95.	0.1	7
67	Strong blue and red luminescence in silicon nanoparticles based light emitting capacitors. <i>Applied Physics Letters</i> , 2011, 99, 171102.	3.3	21
68	Cell analysis using a multiple internal reflection photonic lab-on-a-chip. <i>Nature Protocols</i> , 2011, 6, 1642-1655.	12.0	41
69	Integrated Bimodal Waveguide Interferometric Biosensor for Label-Free Analysis. <i>Journal of Lightwave Technology</i> , 2011, 29, 1926-1930.	4.6	167
70	Metal-nitride-oxide-semiconductor light-emitting devices for general lighting. <i>Optics Express</i> , 2011, 19, A234.	3.4	19
71	Fluorophore-doped xerogel antiresonant reflecting optical waveguides. <i>Optics Express</i> , 2011, 19, 5026.	3.4	4
72	High Q light-emitting Si-rich Si ₃ N ₄ microdisks. <i>Optics Letters</i> , 2011, 36, 1344.	3.3	4

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73	Blue-green to near-IR switching electroluminescence from Si-rich silicon oxide/nitride bilayer structures. <i>Optics Letters</i> , 2011, 36, 2617.	3.3	11
74	Stoichiometry of silicon-rich dielectrics for silicon nanocluster formation. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2011, 8, 804-807.	0.8	4
75	Optically active substoichiometric Si ₃ N ₄ 1/4-cavities. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2011, 8, 1060-1065.	0.8	1
76	UV laser-induced high resolution cleaving of Si wafers for micro-nano devices and polymeric waveguide characterization. <i>Applied Surface Science</i> , 2011, 257, 5424-5428.	6.1	2
77	Blue and red electroluminescence of silicon-rich oxide light emitting capacitors. , 2010, , .		3
78	Silicon nanocrystals light-emitting devices: characterization and coupling to SU-8 waveguides. <i>Proceedings of SPIE</i> , 2010, , .	0.8	1
79	Photoluminescence enhancement through silicon implantation on SRO-LPCVD films. <i>Materials Science and Engineering B: Solid-State Materials for Advanced Technology</i> , 2010, 174, 119-122.	3.5	18
80	Mechanically tuneable microoptical structure based on PDMS. <i>Sensors and Actuators A: Physical</i> , 2010, 162, 260-266.	4.1	7
81	Topographic analysis of silicon nanoparticles-based electroluminescent devices. <i>Materials Science and Engineering B: Solid-State Materials for Advanced Technology</i> , 2010, 174, 123-126.	3.5	4
82	Silicon sensor with high sensibility from 200 to 1100 nm using embedded silicon nano-particles. , 2010, , .		0
83	DC and AC electroluminescence in silicon nanoparticles embedded in silicon-rich oxide films. <i>Nanotechnology</i> , 2010, 21, 085710.	2.6	24
84	Design of a CMOS transducer interface for an UV silicon sensor. , 2010, , .		0
85	Analysis of surface roughness and its relationship with photoluminescence properties of silicon-rich oxide films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2009, 27, 57-62.	2.1	39
86	Cantilever-based poly(dimethylsiloxane) Microoptoelectromechanical Systems. , 2009, , .		1
87	Si-nanocrystal-based LEDs fabricated by ion implantation and plasma-enhanced chemical vapour deposition. <i>Nanotechnology</i> , 2009, 20, 405201.	2.6	34
88	The mechanism of electrical annihilation of conductive paths and charge trapping in silicon-rich oxides. <i>Nanotechnology</i> , 2009, 20, 045201.	2.6	22
89	Biosensing microsystem platforms based on the integration of Si Mach-Zehnder interferometer, microfluidics and grating couplers. , 2009, , .		11
90	Mechanically tuneable microoptical structure based on PDMS. <i>Procedia Chemistry</i> , 2009, 1, 560-563.	0.7	4

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91	Hollow waveguide-based full-field absorbance biosensor. <i>Sensors and Actuators B: Chemical</i> , 2009, 139, 143-149.	7.8	8
92	“Electronic tongue”-integrated sensor system based on an array of ion-selective field-effect transistors for multicomponent analysis of liquid media. <i>Russian Journal of Applied Chemistry</i> , 2009, 82, 1384-1389.	0.5	1
93	Poly(Dimethylsiloxane) Waveguide Cantilevers for Optomechanical Sensing. <i>IEEE Photonics Technology Letters</i> , 2009, 21, 79-81.	2.5	21
94	MNOS structure: towards efficient and reliable silicon nanocrystal-based LEDs. , 2009, , .		0
95	Charge trapping and de-trapping in Si-nanoparticles embedded in silicon oxide films. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2008, 5, 3651-3654.	0.8	5
96	Optical characterization of silicon rich oxide films. <i>Sensors and Actuators A: Physical</i> , 2008, 142, 12-18.	4.1	40
97	Integrated multisensor chip with sequential injection technique as a base for “electronic tongue”-devices. <i>Sensors and Actuators B: Chemical</i> , 2008, 131, 48-52.	7.8	24
98	Characterisation of the interdigitated electrode array with tantalum silicide electrodes separated by insulating barriers. <i>Electrochemistry Communications</i> , 2008, 10, 1621-1624.	4.7	25
99	Three-dimensional interdigitated electrode array as a transducer for label-free biosensors. <i>Biosensors and Bioelectronics</i> , 2008, 24, 729-735.	10.1	51
100	Photoluminescence characterization of silicon nanostructures embedded in silicon oxide. <i>Superlattices and Microstructures</i> , 2008, 43, 588-593.	3.1	7
101	Silicon-based rectangular hollow integrated waveguides. <i>Optics Communications</i> , 2008, 281, 1568-1575.	2.1	5
102	Full-field photonic biosensors based on tunable bio-doped sol-gel glasses. <i>Lab on A Chip</i> , 2008, 8, 1185.	6.0	26
103	3-D modulable PDMS-based microlens system. <i>Optics Express</i> , 2008, 16, 4918.	3.4	14
104	Optical Biosensor Based On Hollow Integrated Waveguides. <i>Analytical Chemistry</i> , 2008, 80, 3498-3501.	6.5	22
105	Patterning High-Aspect-Ratio Sol-Gel Structures by Microtransfer Molding. <i>Chemistry of Materials</i> , 2008, 20, 2662-2668.	6.7	21
106	Coulomb blockade effects in silicon nanoparticles embedded in thin silicon-rich oxide films. <i>Nanotechnology</i> , 2008, 19, 165401.	2.6	15
107	Broad range adjustable emission of stacked SiN _x /SiO _y layers. <i>Journal of Materials Research</i> , 2008, 23, 1513-1516.	2.6	9
108	Auger quenching-based modulation of electroluminescence from ion-implanted silicon nanocrystals. <i>Nanotechnology</i> , 2008, 19, 205201.	2.6	13

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109	Optical waveguide cantilever actuated by light. Applied Physics Letters, 2008, 92, .	3.3	14
110	Efficiency and reliability enhancement of silicon nanocrystal field-effect luminescence from nitride-oxide gate stacks. Applied Physics Letters, 2008, 92, 241104.	3.3	32
111	Silicon Photonic Biosensors for Lab-on-a-Chip Applications. Advances in Optical Technologies, 2008, 2008, 1-6.	0.8	80
112	Dual-wavelength measurement system for absorbance chemical sensing. Measurement Science and Technology, 2007, 18, 3443-3450.	2.6	6
113	Off Stoichiometric Silicon Oxide Applied to Enhance the Silicon Responsivity up to UV Region. , 2007, , .		0
114	Optical biosensor based on arrays of waveguide microcantilevers. , 2007, , .		2
115	Lab-on-a-chip platforms based on highly sensitive nanophotonic Si biosensors for single nucleotide DNA testing. , 2007, , .		6
116	Light emitting devices in the visible obtained by PECVD and ion implantation. , 2007, , .		0
117	Modeling of non-stoichiometric silicon oxides obtained by plasma enhanced chemical vapour deposition process. Thin Solid Films, 2007, 515, 3380-3386.	1.8	8
118	Novel cantilever design with high control of the mechanical performance. Microelectronic Engineering, 2007, 84, 1292-1295.	2.4	4
119	Pulsed electroluminescence in silicon nanocrystals-based devices fabricated by PECVD. Physica E: Low-Dimensional Systems and Nanostructures, 2007, 38, 193-196.	2.7	20
120	Comparative study between silicon-rich oxide films obtained by LPCVD and PECVD. Physica E: Low-Dimensional Systems and Nanostructures, 2007, 38, 54-58.	2.7	47
121	Surface and Interface Structure of Silicon Rich Oxide Films. , 2006, , .		1
122	Microfluidic-optical integrated CMOS compatible devices for label-free biochemical sensing. Journal of Micromechanics and Microengineering, 2006, 16, 1006-1016.	2.6	74
123	Optical biosensor microsystems based on the integration of highly sensitive Machâ€Zehnder interferometer devices. Journal of Optics, 2006, 8, S561-S566.	1.5	154
124	Light coupling into an optical microcantilever by an embedded diffraction grating. Applied Optics, 2006, 45, 229.	2.1	13
125	A novel optical waveguide microcantilever sensor for the detection of nanomechanical forces. Journal of Lightwave Technology, 2006, 24, 2132-2138.	4.6	90
126	Ion beam analysis of PECVD silicon oxide thin films. Nuclear Instruments & Methods in Physics Research B, 2006, 243, 200-204.	1.4	3

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127	A highly sensitive microsystem based on nanomechanical biosensors for genomics applications. Sensors and Actuators B: Chemical, 2006, 118, 2-10.	7.8	68
128	Butt coupled microcantilever in sensing applications. , 2006, 6186, 55.		1
129	T-shaped microcantilever sensor with reduced deflection offset. Applied Physics Letters, 2006, 89, 094109.	3.3	16
130	Dimension dependence of the thermomechanical noise of microcantilevers. Journal of Applied Physics, 2006, 99, 024910.	2.5	24
131	Field effect luminescence from Si nanocrystals obtained by plasma-enhanced chemical vapor deposition. Applied Physics Letters, 2006, 89, 051112.	3.3	65
132	Compositional study of Silicon Rich Oxide films.. , 2006, , .		0
133	Magnetism and magneto-optics of Co nanoparticles embedded in dielectric and metallic matrices. , 2005, , .		1
134	Diffraction grating couplers milled in Si3N4 rib waveguides with a focused ion beam. Optics Express, 2005, 13, 8618.	3.4	10
135	Chemical Multi-Sensor Arrays for Liquids Monolithic Integration Using Microelectronic Technology. , 2005, , 273-289.		1
136	Absorbance-Based Integrated Optical Sensors. , 2005, , 1-44.		3
137	Integrated Micro/Nano-optical Biosensor devices Si CMOS compatible for microsystem applications. , 2005, , .		0
138	Absorbance-Based Integrated Optical Sensors. , 2005, , 1-44.		0
139	Precipitation of highly luminescent phases from PECVD Si suboxides. Materials Research Society Symposia Proceedings, 2004, 832, 303.	0.1	2
140	Integrated micro- and nano-optical biosensor silicon devices CMOS compatible. , 2004, 5357, 96.		7
141	Nanostructures for chemical recognition using ISFET sensors. Microelectronics Journal, 2004, 35, 69-71.	2.0	6
142	Optical properties of silicon rich silicon oxides obtained by PECVD. Microelectronics Journal, 2004, 35, 65-67.	2.0	5
143	Silicon excess and thermal annealing effects on the photoluminescence of SiO2 and silicon rich oxide super enriched with siliccon implantation. Physica Status Solidi C: Current Topics in Solid State Physics, 2004, 1, S83-S87.	0.8	18
144	Technological aspects on the fabrication of silicon-based optical accelerometer with ARROW structures. Sensors and Actuators A: Physical, 2004, 110, 395-400.	4.1	9

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145	Investigation of chloride sensitive ISFETs with different membrane compositions suitable for medical applications. <i>Analytica Chimica Acta</i> , 2004, 514, 99-106.	5.4	57
146	BESOI-Based Integrated Optical Silicon Accelerometer. <i>Journal of Microelectromechanical Systems</i> , 2004, 13, 355-364.	2.5	37
147	Characterization and Passivation Effects of an Optical Accelerometer Based on Antiresonant Waveguides. <i>IEEE Photonics Technology Letters</i> , 2004, 16, 233-235.	2.5	10
148	Simple Estimation of Transition Losses in Bends of Wide Optical Waveguides by a Ray Tracing Method. <i>IEEE Photonics Technology Letters</i> , 2004, 16, 825-827.	2.5	10
149	Large-Core Single-Mode Waveguides With Cross-Sectional Antiresonant Confinement. <i>Journal of Lightwave Technology</i> , 2004, 22, 1560-1565.	4.6	5
150	Lowering the detection limit of calcium selective ISFETs with polymeric membranes. <i>Talanta</i> , 2004, 62, 91-96.	5.5	12
151	Development of a multiparametric system based on solid-state microsensors for monitoring a nuclear waste repository. <i>Sensors and Actuators B: Chemical</i> , 2003, 91, 103-108.	7.8	6
152	Development of a multiparametric analyser based on ISFET sensors applied to process control in the wine industry. <i>Sensors and Actuators B: Chemical</i> , 2003, 89, 199-204.	7.8	22
153	Integrated Mach-Zehnder interferometer based on ARROW structures for biosensor applications. <i>Sensors and Actuators B: Chemical</i> , 2003, 92, 151-158.	7.8	109
154	An integrated optical interferometric nanodevice based on silicon technology for biosensor applications. <i>Nanotechnology</i> , 2003, 14, 907-912.	2.6	279
155	Chalcogenide glass-based rib ARROW waveguide. <i>Journal of Non-Crystalline Solids</i> , 2003, 326-327, 455-459.	3.1	23
156	Effect of hydrogen-related impurities on the thermal behavior of mechanical stress in silicon oxides suitable for integrated optics. <i>Journal of Applied Physics</i> , 2003, 93, 5125-5130.	2.5	18
157	Chapter 13 Integrated optical transducers for (bio)chemical sensing. <i>Comprehensive Analytical Chemistry</i> , 2003, , 541-586.	1.3	1
158	Integrated optical silicon IC compatible nanodevices for biosensing applications. , 2003, , .		5
159	Improved Integrated Waveguide Absorbance Optodes for Ion-Selective Sensing. <i>Analytical Chemistry</i> , 2002, 74, 3354-3361.	6.5	30
160	Effect of wall tilt on the optical properties of integrated directional couplers. <i>Optics Letters</i> , 2002, 27, 601.	3.3	4
161	Electrochemical platinum coatings for improving performance of implantable microelectrode arrays. <i>Biomaterials</i> , 2002, 23, 4515-4521.	11.4	46
162	Optimized silicon antiresonant reflecting optical waveguides for sensing applications. <i>Journal of Lightwave Technology</i> , 2001, 19, 75-83.	4.6	37

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163	Electrostatic discharge sensitivity tests for ISFET sensors. <i>Sensors and Actuators B: Chemical</i> , 2001, 80, 255-260.	7.8	8
164	Application of ion sensitive field effect transistor based sensors to soil analysis. <i>Computers and Electronics in Agriculture</i> , 2001, 31, 281-293.	7.7	97
165	LUMINESCENCE STUDIES IN THERMAL OXIDE FILMS WITH Si IMPLANTATION. <i>Modern Physics Letters B</i> , 2001, 15, 704-707.	1.9	1
166	Ion-selective field effect transistor (ISFET)-based calcium ion sensor with photocured polyurethane membrane suitable for ionised calcium determination in milk. <i>Analytica Chimica Acta</i> , 2000, 408, 57-64.	5.4	44
167	Evolution of the mechanical stress on PECVD silicon oxide films under thermal processing. <i>Journal of Materials Science Letters</i> , 2000, 19, 1399-1401.	0.5	5
168	<title>Mechanical properties of PECVD silicon oxide films suitable for integrated optics applications</title>. , 2000, , .		1
169	Characterization of antiresonant reflecting optical waveguide devices by scanning near-field optical microscopy. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 2000, 17, 2243.	1.5	1
170	Design and analysis of silicon antiresonant reflecting optical waveguides for evanescent field sensor. <i>Journal of Lightwave Technology</i> , 2000, 18, 966-972.	4.6	62
171	Application of an ion-selective field effect transistor with a photocured polymer membrane in nephrology for determination of potassium ions in dialysis solutions and in blood plasma. <i>Talanta</i> , 2000, 52, 533-538.	5.5	20
172	The effect of rapid thermal annealing on properties of plasma enhanced CVD silicon oxide films. <i>Thin Solid Films</i> , 1999, 346, 202-206.	1.8	20
173	ISE and ISFET microsensors based on a sensitive chalcogenide glass for copper ion detection in solution. <i>Sensors and Actuators B: Chemical</i> , 1999, 59, 123-127.	7.8	31
174	Analysis of optochemical absorbance sensors based on bidimensional planar ARROW microoptics. <i>Sensors and Actuators B: Chemical</i> , 1999, 60, 191-199.	7.8	16
175	Plasma enhanced CVD silicon oxide films for integrated optic applications. <i>Vacuum</i> , 1999, 52, 395-400.	3.5	37
176	Ellipsometry on Very Thick Multilayer Structures. <i>Physica Status Solidi (B): Basic Research</i> , 1999, 215, 247-251.	1.5	9
177	Integrated Waveguide Absorbance Optode for Chemical Sensing. <i>Analytical Chemistry</i> , 1999, 71, 5037-5044.	6.5	38
178	Characterisation of complex multilayer structures using spectroscopic ellipsometry. <i>European Physical Journal Special Topics</i> , 1999, 09, Pr8-1195-Pr8-1202.	0.2	0
179	Tone control in dry development of photosensitive polyimides. <i>Vacuum</i> , 1998, 49, 35-41.	3.5	1
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